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1. A processing system, comprising:
 - a plurality of processing units for performing predetermined processing for a substrate;
 - a transfer apparatus for transferring the substrate at least between said processing units; and
 - first image pickup means, provided on said transfer apparatus, for picking-up an image of the inside of said processing units.
2. The processing system as set forth in claim 1, wherein said processing unit is provided with second image pickup means for picking-up an image of a position which said first image pickup means is unable to pick-up.
3. The processing system as set forth in claim 1, wherein said first image pickup means comprises at least a CCD camera and a turn drive mechanism for turning the CCD camera on a horizontal plane.
4. The processing system as set forth in claim 3, wherein said first image pickup means comprises a mechanism for tilting the CCD camera downward.
5. The processing system as set forth in claim 3, wherein said first image pickup means further comprises a forward and rearward drive mechanism for driving at least the CCD camera and the turn drive mechanism forward and rearward in relation to said processing unit.

6. The processing system as set forth in claim 1,
wherein said transfer apparatus comprises a hold
pin movable forward and rearward in relation to said
processing unit while holding the substrate and an
ascent and descent drive mechanism for driving the hold
pin up and down, and

wherein said first image pickup means is driven up
and down together with the hold pin by the ascent and
descent drive mechanism.

7. The processing system as set forth in claim 1,
wherein said first image pickup means comprises a
plurality of kinds of image pickup apparatuses.

8. The processing system as set forth in claim 1,
wherein said system has an automatic mode for
causing said first image pickup means to pick-up an
image of a predetermined position in said processing
unit in predetermined procedures and a manual mode for
causing said first image pickup means to pick-up an
image of a desired position in said processing unit
through manual running operations.

9. The processing system as set forth in claim 1,
wherein in said processing units, there are liquid
system processing units each for performing liquid
processing for the substrate and thermal system
processing units each for performing thermal processing
for the substrate, and

wherein said first image pickup means is used for

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monitoring processing processes for the liquid system processing units and for monitoring a physical position of the substrate for the thermal system processing units.

10. The processing system as set forth in claim 9, wherein monitoring the processing processes for the liquid system processing units includes at least monitoring liquid processing based on an image pickup result of the surface of the substrate by said first image pickup means.

11. The processing system as set forth in claim 10, wherein monitoring the liquid processing is performed based on a color tone or color shading in the surface of the liquid processed substrate.

12. The processing system as set forth in claim 1, wherein said processing unit has a spin chuck rotating while holding the substrate and having a rotation shaft and a nozzle for supplying a processing solution nearly onto the center of the held and rotated substrate, and

wherein said system has means for monitoring whether or not the processing solution is supplied nearly onto the center of the substrate based on an image pickup result by said first image pickup means.

13. The processing system as set forth in claim 12, wherein the surface of the rotation shaft is provided with a center line,

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wherein said system has means for monitoring whether or not the processing solution is supplied nearly onto the center of the substrate.

wherein said first image pickup means picks-up an image of the processing solution supplied from the nozzle onto the substrate, and

15. The processing system as set forth in claim 1,

wherein said first image pickup means picks-up an image of the tip of the nozzle, and

16. The processing system as set forth in claim 1,

wherein said first image pickup means has a laser displacement measurement apparatus for monitoring an extending state of the processing solution supplied onto the held and rotated substrate.

wherein said processing unit has a processing plate for performing heating or cooling processing for the substrate,

wherein said system has means for monitoring whether or not the substrate is placed on a predetermined position on the processing plate based on an image pickup result by said first image pickup means.